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APPLICANTS

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\*\* CONTINUING DATA \*\*\*\*\*  
*No no.*

\*\* FOREIGN APPLICATIONS \*\*\*\*\*  
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*verified. EP*

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Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and Acknowledged	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance <i>[Signature]</i> <i>EP</i> Examiner's Signature Initials	STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 15	TOTAL CLAIMS 26	INDEPENDENT CLAIMS 4
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TITLE  
 Method of forming oxide layer using atomic layer deposition method and method of forming capacitor of semiconductor device using the same

<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees ( Filing )
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